

# Chapter 1. The Devices: Diode and MOS Transistors (Chapter 3 in textbook)

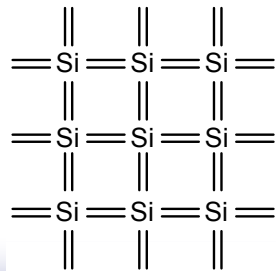
[Adapted from Rabaey's *Digital Integrated Circuits*, ©2002, J. Rabaey et al.]

## Goal of this chapter

- ❑ Present intuitive understanding of device operation
- ❑ Introduction of basic device equations
- ❑ Introduction of models for manual analysis
- ❑ Introduction of models for SPICE simulation
- ❑ Analysis of secondary and deep-sub-micron effects
- ❑ Future trends

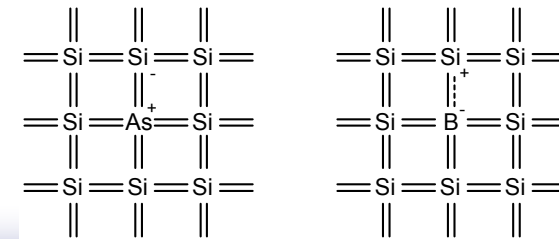
## Semiconductors

- ❑ Semiconductor: electrical conductivity greater than insulator, but less than conductor.
- ❑ Typical semiconductor materials: Si, Ge, GaAs, etc.
- ❑ Transistors are built on a silicon (Si) substrate
- ❑ Silicon is a Group IV semiconductor material
- ❑ Forms crystal lattice with bonds to four neighbors



## Silicon Material

- ❑ Pure silicon: very few free carriers, conducts poorly
- ❑ Intrinsic Si (undoped):  
 $n = p = n_i = 1.5 \times 10^{10} / \text{cm}^3$  (room temperature)  
 where  $n$  ( $p$ ): free-electron(hole) concentration,  
 $n_i$ : intrinsic carrier concentration.
- ❑ Adding dopants increases the conductivity
  - ✓ Group V dopants: contribute extra electron (n-type)
  - ✓ Group III dopants: contribute hole (missing electron, p-type)

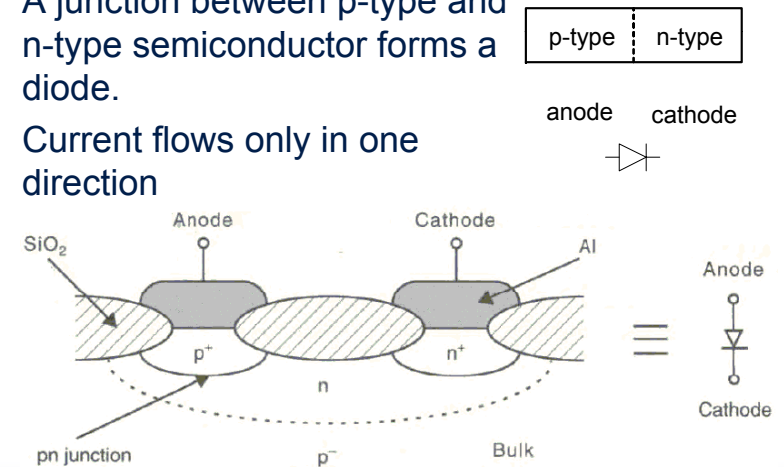


## Dopants

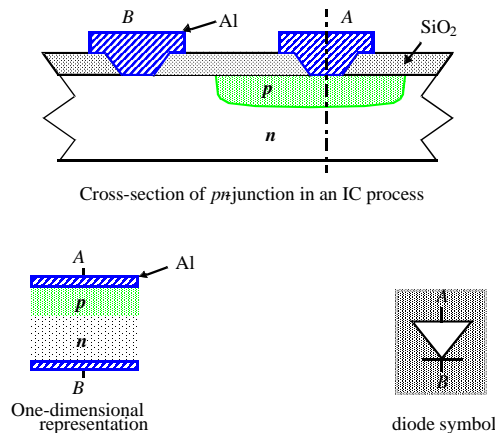
- Donor: impurity with valence  $\geq 5$  (e.g. P, As)  $\Rightarrow$  n-type with free electrons. Assume doping concentration of donor as  $N_D$ .
  - 1). Concentration of free electrons in n-type material ( $n_n$ ):  
 $n_n = N_D \gg n_i$
  - 2). Concentration of free holes in n-type material ( $p_n$ ):  
 $p_n = n_i^2 / N_D$
- Acceptor: impurity with valence  $\leq 3$  (e.g. B)  $\Rightarrow$  p-type with free holes. Assume doping concentration of acceptor as  $N_A$ .
  - 1). Concentration of free holes in p-type material ( $p_p$ ):  
 $p_p = N_A \gg n_i$
  - 2). Concentration of free electrons in p-type material ( $n_p$ ):  
 $n_p = n_i^2 / N_A$

## p-n Junctions

- A junction between p-type and n-type semiconductor forms a diode.
- Current flows only in one direction

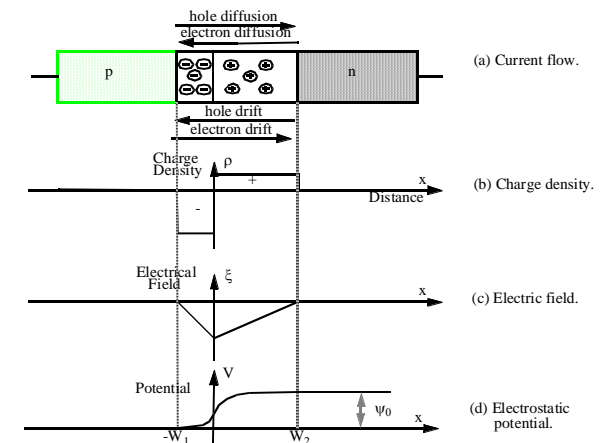


## The Diode



Mostly occurring as parasitic element in Digital ICs

## Depletion Region



## PN Junction

- Built-in potential of PN junction:  $\Phi_0 = V_T \ln\left(\frac{N_A N_D}{n_i^2}\right)$   
 where the thermal voltage  $V_T = kT/q$ , in it,  
 k: Boltzmann constant,  $k = 1.38 \times 10^{-23} \text{ m}^2 \cdot \text{kg} \cdot \text{s}^{-2} \cdot \text{K}^{-1}$ ,  
 q: electron charge,  $q = 1.6 \times 10^{-19} \text{ C}$ .  
 At room temperature ( $T = 300\text{K}$ ),  $V_T = 0.026\text{V}$ .

## Reversed-biased Diode: Depletion Width

### • Depletion Width

use Poisson's equation & charge neutrality

$$- W = x_p + x_n$$

$$x_p = \left[ \frac{2\epsilon(\Psi_0 + V_R)N_D}{qN_A(N_D + N_A)} \right]^{1/2} \quad x_n = \left[ \frac{2\epsilon(\Psi_0 + V_R)N_A}{qN_D(N_D + N_A)} \right]^{1/2}$$

• where  $V_R$  is applied reverse bias

$$W = \left[ \frac{2\epsilon(\Psi_0 + V_R)(N_D + N_A)}{qN_D N_A} \right]^{1/2}$$

$\epsilon$  is the permittivity of Si  $\Psi_0 = V_T \ln\left(\frac{N_A N_D}{n_i^2}\right)$   
 $\epsilon = 1.04 \times 10^{-12} \text{ F/cm}$   
 $\epsilon = K_S \epsilon_0$ , where  $\epsilon_0 = 8.85 \times 10^{-14} \text{ F/cm}$   
 and  $K_S = 11.8$  is the relative permittivity of silicon

### • One-sided Step Junction

- if  $N_A \gg N_D$  (p+n diode)

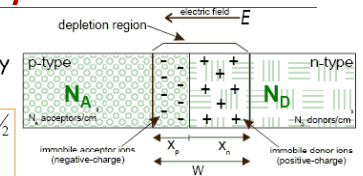
• most of junction on n-side

$$W \cong x_n = \left[ \frac{2\epsilon(\Psi_0 + V_R)}{qN_D} \right]^{1/2}$$

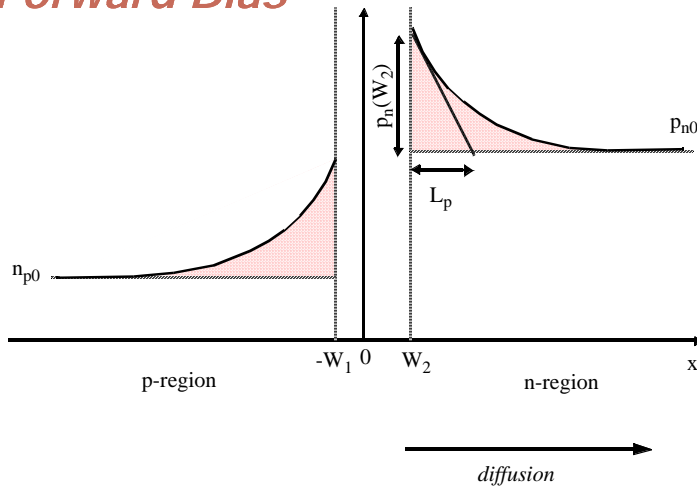
- if  $N_D \gg N_A$  (n+p diode)

• most of junction on p-side

$$W \cong x_p = \left[ \frac{2\epsilon(\Psi_0 + V_R)}{qN_A} \right]^{1/2}$$

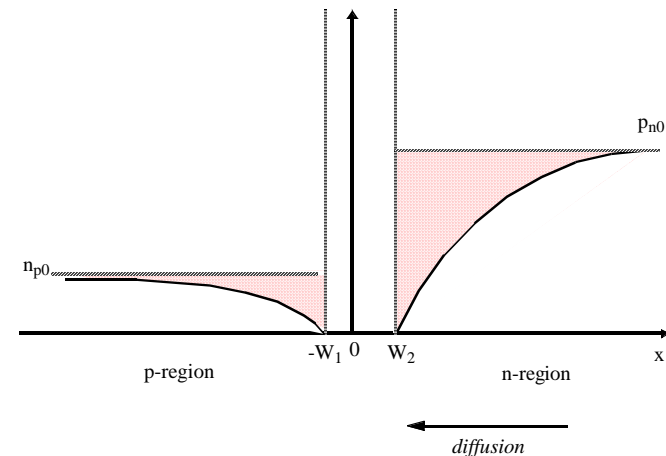


## Forward Bias




Typically avoided in Digital ICs

## Reverse Bias



The Dominant Operation Mode

## Forward-biased Junction

- Drift current: current flow due to concentration gradient of the minority charge near junction
- Forward-bias current under forward-bias voltage  $V_D$ : 

$$I_D = I_S \left( e^{V_D/V_T} - 1 \right) \quad I_S \propto A \left( \frac{1}{N_D} + \frac{1}{N_A} \right)$$

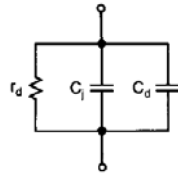
- Small-signal model of forward-biased diode

$$1) \text{ Incremental resistance } r_d \quad \frac{1}{r_d} = \frac{dI_D}{dV_D} = I_S \frac{e^{V_D/V_T}}{V_T} = \frac{I_D}{V_T}$$

- 2). Depletion capacitance  $C_j$ : for depletion width change and immobile charge change in depletion region.

- 3). Diffusion capacitance  $C_d$ : for minority carrier concentration change close to junction.

$\tau_T$ : transition time of diode (specified for a given technology)



$$C_d = \frac{\tau_T}{r_d}$$

## Reverse Bias Diode

- The **ideal diode equation** (for both forward and reverse-bias conditions) is:

$$I_D = I_S (e^{V_D/\phi_T} - 1)$$

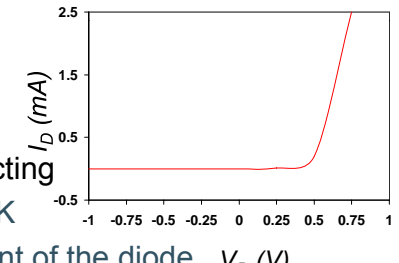
where  $V_D$  is the voltage applied to the junction - 

- a forward-bias lowers the potential barrier allowing carriers to flow across the diode junction

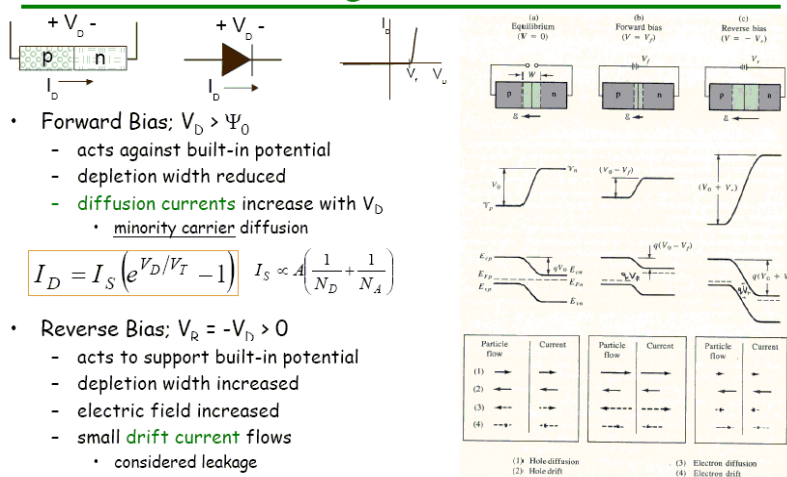
- a reverse-bias raises the potential barrier and the diode becomes non-conducting

$$\phi_T = kT/q = 26\text{mV at } 300\text{K}$$

$I_S$  is the saturation current of the diode  $V_D$  (V)



## Diode Biasing and Current Flow

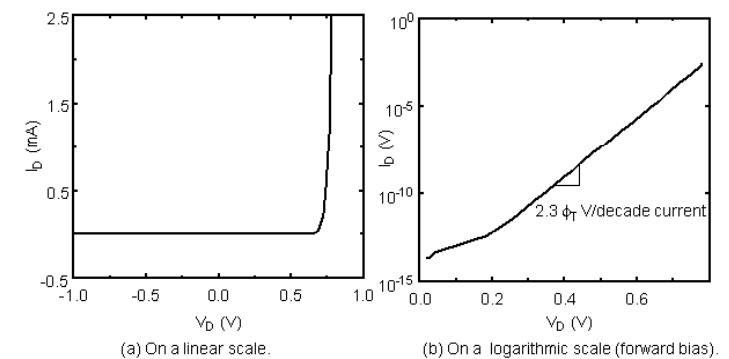


- Forward Bias:**  $V_D > \Psi_0$ 
  - acts against built-in potential
  - depletion width reduced
  - diffusion currents increase with  $V_D$ 
    - minority carrier diffusion

$$I_D = I_S \left( e^{V_D/V_T} - 1 \right) \quad I_S \propto A \left( \frac{1}{N_D} + \frac{1}{N_A} \right)$$

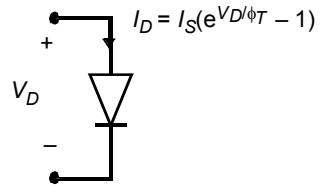
- Reverse Bias:**  $V_R = -V_D > 0$ 
  - acts to support built-in potential
  - depletion width increased
  - electric field increased
  - small drift current flows
    - considered leakage
    - small until  $V_R$  is too high and breakdown occurs

## Diode Current

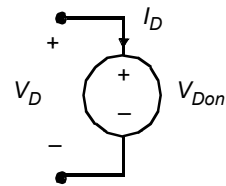


$$I_D = I_S \left( e^{V_D/\phi_T} - 1 \right)$$

# Models for Manual Analysis



(a) Ideal diode model



(b) First-order diode model

# Junction Depletion Capacitance

- Depletion capacitance: capacitance due to varying charge storage in depletion regions.
- Reason: bias voltage changes => junction widths change => charge in depletion region changes => capacitance effect.
- Depletion capacitance:

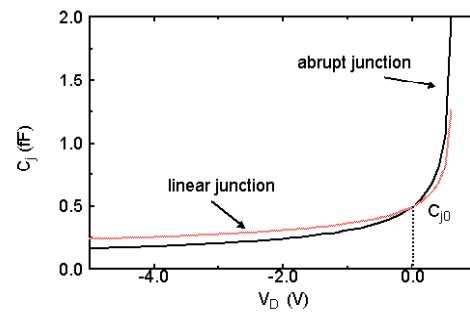
$$C_1 = \frac{dQ^+}{dV_R} = \left[ \frac{qK_s\epsilon_0 N_A N_D}{2(\Phi_0 + V_R)N_A + N_D} \right]^{1/2} = \frac{C_{j0}}{\sqrt{1 + \frac{V_R}{\Phi_0}}} \quad C_{j0} = \sqrt{\frac{qK_s\epsilon_0 N_A N_D}{2\Phi_0}}$$

$C_{j0}$ : depletion capacitance per unit area at  $V_R=0$ .

If  $N_A \gg N_D$  (one-side diode):

$$C_1 = \left[ \frac{qK_s\epsilon_0 N_D}{2(\Phi_0 + V_R)} \right]^{1/2} = \frac{C_{j0}}{\sqrt{1 + \frac{V_R}{\Phi_0}}} \quad \text{where } C_{j0} = \sqrt{\frac{qK_s\epsilon_0 N_D}{2\Phi_0}}$$

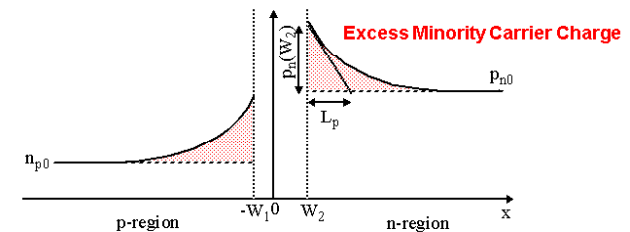
# Junction Capacitance



$$C_j = \frac{C_{j0}}{(1 - V_D/\phi_0)^m}$$

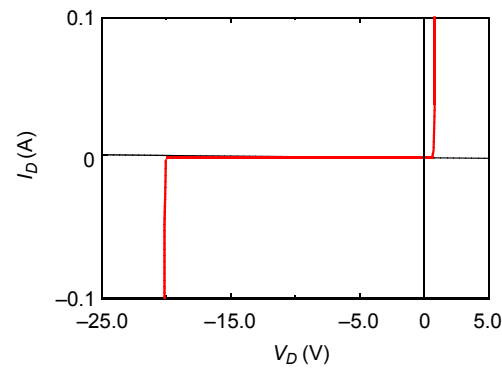
$m = 0.5$ : abrupt junction  
 $m = 0.33$ : linear junction

# Diffusion Capacitance



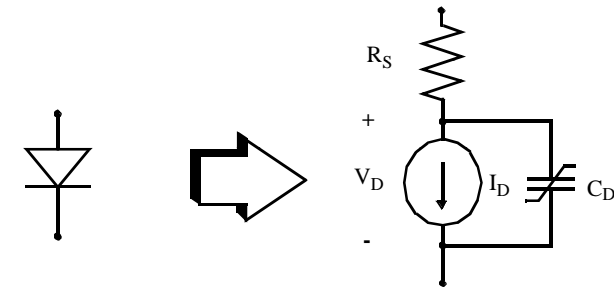
$$C_d = \frac{dQ_D}{dV_D} = \tau_T \frac{dI_D}{dV_D} \approx \frac{\tau_T I_D}{\phi_T}$$

## Secondary Effects



**Avalanche Breakdown**

## Diode Model

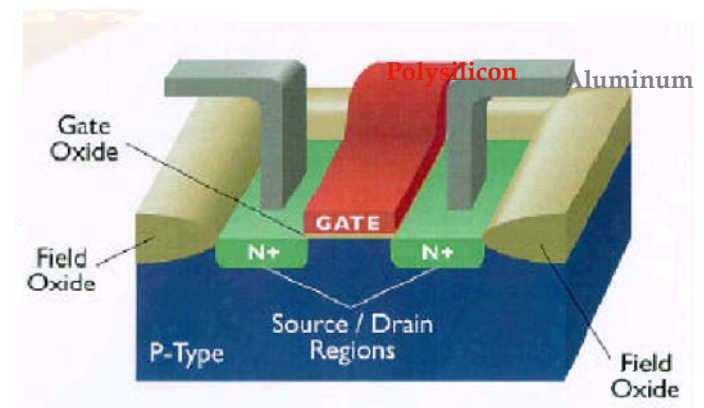


## SPICE Parameters

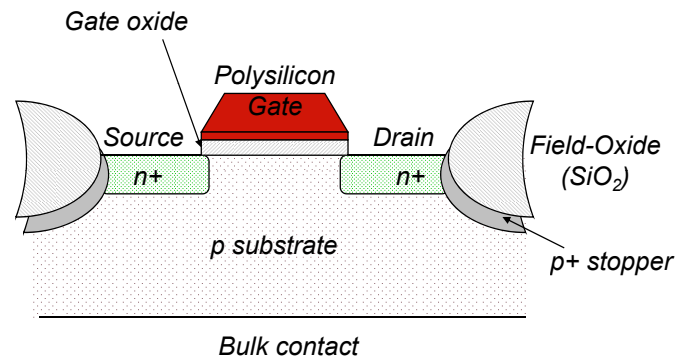
Parameter Name	Symbol	SPICE Name	Units	Default Value
Saturation current	$I_S$	IS	A	1.0 E-14
Emission coefficient	$n$	N	-	1
Series resistance	$R_S$	RS	$\Omega$	0
Transit time	$\tau_T$	TT	sec	0
Zero-bias junction capacitance	$C_{j0}$	CJ0	F	0
Grading coefficient	$m$	M	-	0.5
Junction potential	$\phi_0$	VJ	V	1

First Order SPICE diode model parameters.

## Device: The MOS Transistor



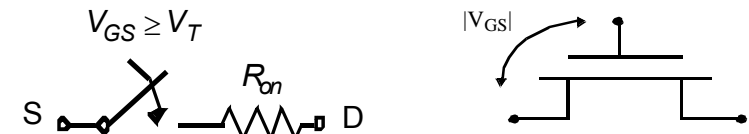
## Device: The MOS Transistor



CROSS-SECTION of NMOS Transistor

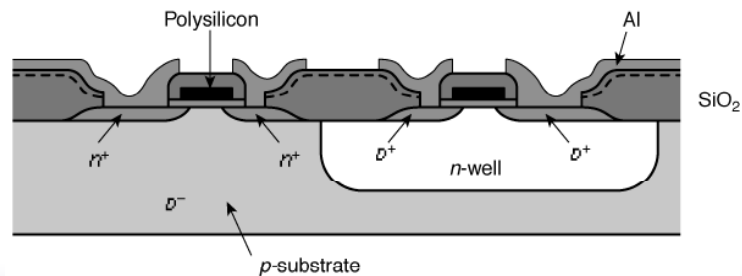
## What is a Transistor?

A Switch!  $\longleftrightarrow$  An MOS Transistor

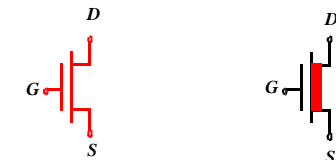


## Power Supply Voltage for CMOS

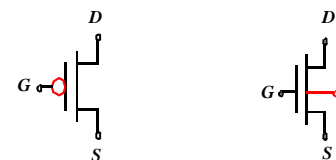
- $GND = 0 V$
- In 1980's,  $V_{DD} = 5V$
- $V_{DD}$  has decreased in modern processes
  - High  $V_{DD}$  would damage modern tiny transistors
  - Lower  $V_{DD}$  saves power
- $V_{DD} = 3.3V, 2.5V, 1.8V, 1.5V, 1.2V, 1.0V, \dots$



## MOS Transistors - Types and Symbols

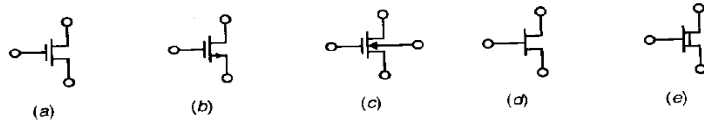


NMOS Enhancement NMOS Depletion

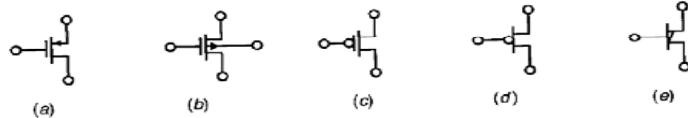


PMOS Enhancement NMOS with Bulk Contact

## MOS transistors: Types and Symbols



Commonly used symbols for n-channel transistor



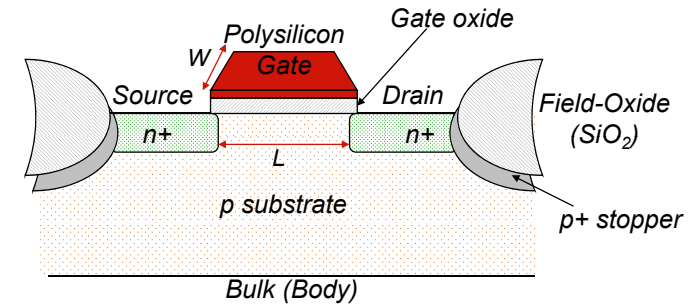
### • Bulk connection:

✓ NMOS: bulk is generally connected to the lowest voltage level available in the circuit (Gnd for digital VLSI,  $-V_{SS}$  for analog VLSI).

✓ PMOS: bulk is generally connected to the highest voltage level in the circuit ( $V_{dd}$  for digital VLSI,  $+V_{SS}$  for analog VLSI)

## The NMOS Transistor Cross Section

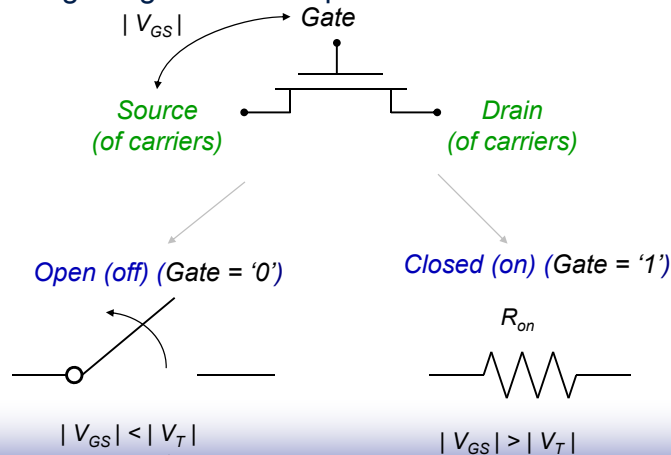
*n* areas have been doped with **donor** ions (arsenic) of concentration  $N_D$  - electrons are the majority carriers



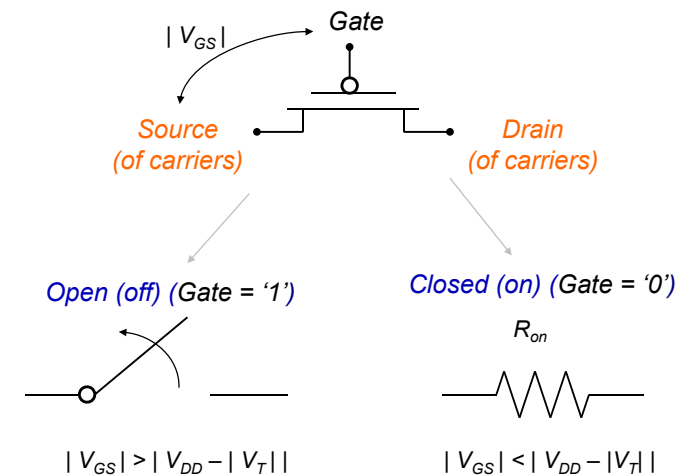
*p* areas have been doped with **acceptor** ions (boron) of concentration  $N_A$  - holes are the majority carriers

## Switch Model of NMOS Transistor

- We can view MOS transistors as electrically controlled switches
- Voltage at gate controls path from source to drain



## Switch Model of PMOS Transistor





## MOSFET Gate Operation

### Gate Capacitance $C_G$

- gate-substrate parallel plate capacitor

$$C_G = \epsilon_{ox} A_G / t_{ox} \text{ [F]}$$

- $\epsilon_{ox}$ : dielectric constant of gate oxide
- $\epsilon_0$ : dielectric constant of vacuum

$$\epsilon_{ox} = 3.9 \epsilon_0$$

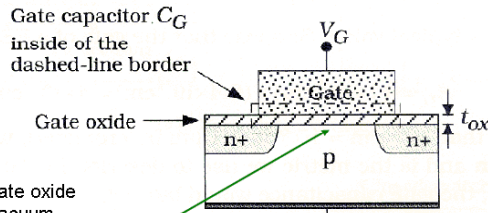
$$\epsilon_0 = 8.85 \times 10^{-14} \text{ [F/cm]}$$

- $A_G$ : gate area =  $L \cdot W$  [ $\text{cm}^2$ ]
- $t_{ox}$ : gate oxide thickness

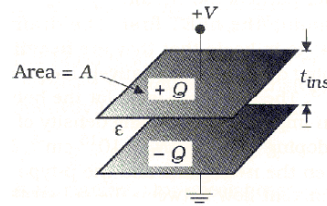
### Oxide capacitance per unit area - $C_{OX}$

$$C_{OX} = \epsilon_{ox} / t_{ox} \text{ [F/cm}^2\text{]}$$

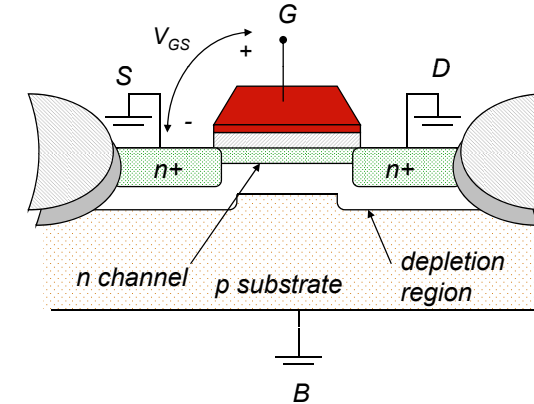
$$C_G = C_{OX} A_G \text{ [F]}$$



**channel** = substrate region under the gate, between S and D



## Threshold Voltage Concept



- Depletion region: area devoid of mobile carriers (holes)
- Inversion region: n-channel region under oxide
- The value of  $V_{GS}$  where strong inversion occurs is called the threshold voltage,  $V_T$

## The Threshold Voltage

where

$$V_T = V_{T0} + \gamma(\sqrt{|-2\phi_F + V_{SB}|} - \sqrt{|-2\phi_F|})$$

$V_{T0}$  is the threshold voltage at  $V_{SB} = 0$  and is mostly a function of the manufacturing process

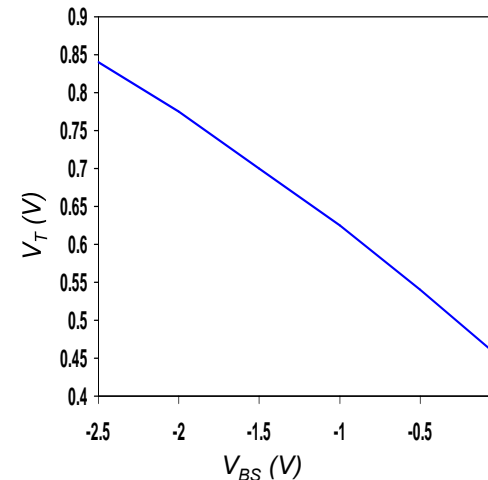
- Difference in work-function between gate and substrate material, oxide thickness, Fermi voltage, charge of impurities trapped at the surface, dosage of implanted ions, etc.

$V_{SB}$  is the source-bulk voltage

$\phi_F = -\phi_T \ln(N_A/n_i)$  is the Fermi potential ( $\phi_T = kT/q = 26\text{mV}$  at 300K is the thermal voltage;  $N_A$  is the acceptor ion concentration;  $n_i \approx 1.5 \times 10^{10} \text{ cm}^{-3}$  at 300K is the intrinsic carrier concentration in pure silicon)

$\gamma = \sqrt{(2q\epsilon_{si}N_A)/C_{OX}}$  is the body-effect coefficient (impact of changes in  $V_{SB}$ ) ( $\epsilon_{si} = 1.053 \times 10^{-10} \text{ F/m}$  is the permittivity of silicon;  $C_{OX} = \epsilon_{ox}/t_{ox}$  is the gate oxide capacitance with  $\epsilon_{ox} = 3.5 \times 10^{-11} \text{ F/m}$ )

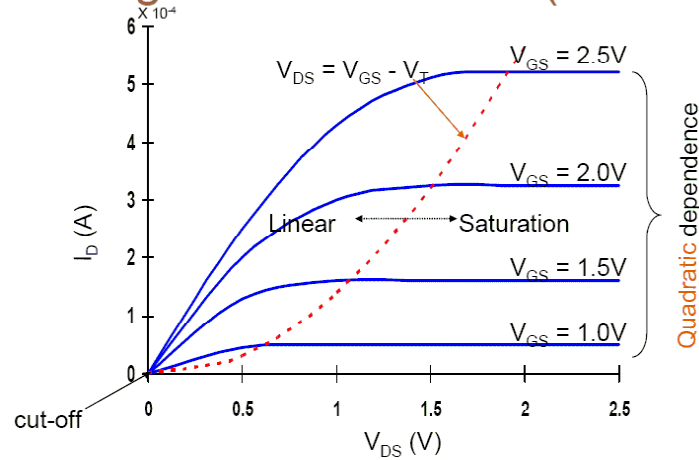
## The Body Effect



- $V_{SB}$  is the substrate bias voltage (normally positive for n-channel devices with the body tied to ground)

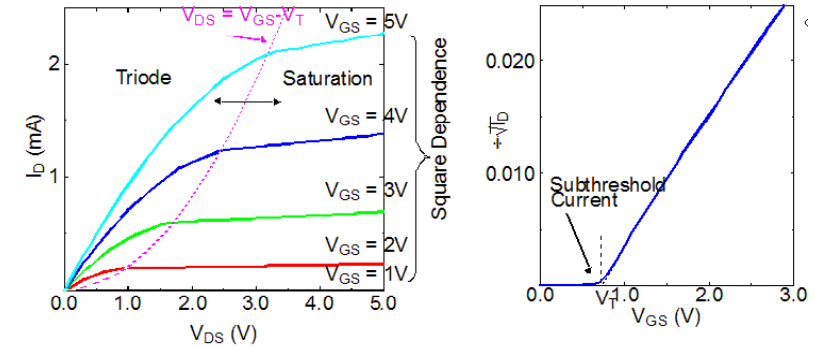
- A negative bias causes  $V_T$  to increase from 0.45V to 0.85V

## Long Channel I-V Plot (NMOS)



NMOS transistor,  $0.25\mu\text{m}$ ,  $L_d = 10\mu\text{m}$ ,  $W/L = 1.5$ ,  $V_{DD} = 2.5\text{V}$ ,  $V_T = 0.4\text{V}$

## Long Channel I-V Relation (NMOS)



(a)  $I_D$  as a function of  $V_{DS}$

(b)  $\sqrt{I_D}$  as a function of  $V_{GS}$  (for  $V_{DS} = 5\text{V}$ ).

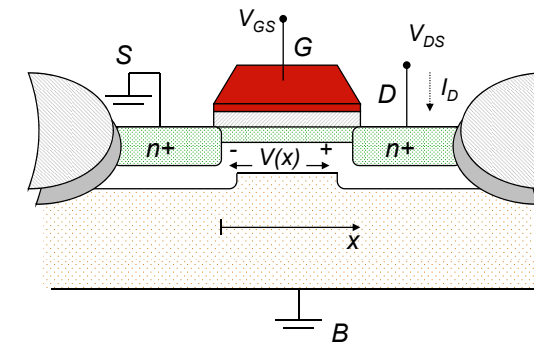
NMOS Enhancement Transistor:  $W = 100\mu\text{m}$ ,  $L = 20\mu\text{m}$

## MOSFET Operating Regions

- Strong inversion when  $V_{GS} > V_T$ 
  - Linear (resistive) when  $V_{DS} < V_{DS-sat}$
  - Saturated (constant current) when  $V_{DS} \geq V_{DS-sat}$
- Weak inversion (sub-threshold) when  $V_{GS} \leq V_T$ 
  - Exponential in  $V_{GS}$  with linear  $V_{DS}$  dependence
- $V_{DS-sat}$ : Drain-source voltage when the channel becomes pinched off.  $V_{DS-sat} = V_{GS} - V_T$
- Transconductance
  - process transconductance,  $k'_n = \mu_n C_{ox}$  (for NMOS),  $k'_p = \mu_p C_{ox}$  (for PMOS).
    - constant for a given fabrication process
  - device transconductance,  $\beta_n = k'_n W/L$  (for NMOS),  $\beta_p = k'_p W/L$  (for PMOS).

## Transistor in Linear Mode

Assuming  $V_{GS} > V_T$



- When  $V_{GS} > V_T$  and  $V_{DS} < V_{GS} - V_T$  a current flows from drain to source
- The current is a linear function of both  $V_{GS}$  and  $V_{DS}$

## Voltage-Current Relation: Linear Mode

For long-channel devices ( $L > 0.25$  micron)

□ When  $V_{DS} \leq V_{GS} - V_T$

$$I_D = k'_n W/L [(V_{GS} - V_T)V_{DS} - V_{DS}^2/2]$$

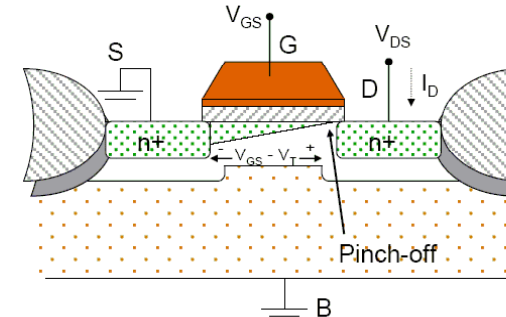
where

$k'_n = \mu_n C_{ox} = \mu_n \epsilon_{ox} / t_{ox}$  is the **process transconductance parameter** ( $\mu_n$  is the carrier mobility ( $m^2/Vsec$ ))

$k_n = k'_n W/L$  is the **gain factor** of the device

For small  $V_{DS}$ , there is a linear dependence between  $V_{DS}$  and  $I_D$ , hence the name **resistive** or **linear** region

## Transistor in Saturation Mode



Assuming  $V_{GS} > V_T$   
 $V_{DS} > V_{GS} - V_T$

- When charge in the inversion layer=0, number of mobile electrons at drain reduces drastically. This is **pinch-off**
- Number of carriers arriving at pinch-off point from source remain the same → current flowing from drain to source remains constant.
- Increasing  $V_{DS}$  beyond  $V_{GS} - V_T$  causes the depletion region at drain to grow → effective channel length  $L$  decreases
- Since  $I_D$  is inversely proportional to  $L$ , as  $L$  decreases,  $I_D$  increases, but compared to linear mode, it is relatively constant

## Voltage-Current Relation: Saturation Mode

For long channel devices

□ When  $V_{DS} \geq V_{GS} - V_T$

$$I_D' = k'_n/2 W/L [(V_{GS} - V_T)^2]$$

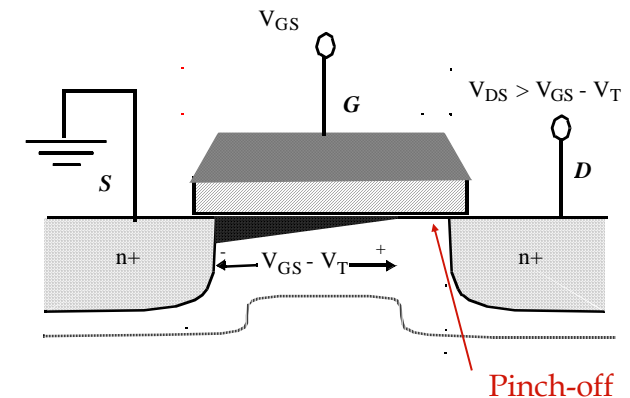
since the voltage difference over the induced channel (from the **pinch-off** point to the source) remains fixed at  $V_{GS} - V_T$

□ However, the effective length of the conductive channel is modulated by the applied  $V_{DS}$ , so

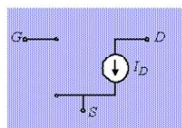
$$I_D = I_D' (1 + \lambda V_{DS})$$

where  $\lambda$  is the **channel-length modulation** (varies with the inverse of the channel length)

## Transistor in Saturation



## Current-Voltage Relations



$$V_T = V_{T0} + \gamma(\sqrt{|-2\phi_F + V_{SB}|} - \sqrt{|-2\phi_F|})$$

$$V_{DS-sat} = V_{GS} - V_T = V_{eff}$$

1). Linear (Triode) Region:  $V_{GS} > V_T, V_{DS} \leq V_{GS} - V_T$

$$I_D = k'_n \frac{W}{L} \left[ (V_{GS} - V_T)V_{DS} - \frac{V_{DS}^2}{2} \right]$$

with  $k'_n = \mu_n C_{ox} = \frac{\mu_n \epsilon_{ox}}{t_{ox}} \Rightarrow$  Process Transconductance Parameter

2). Saturation (Active) Region:  $V_{GS} > V_T, V_{DS} \geq V_{GS} - V_T$

$$I_D = \frac{k'_n W}{2L} (V_{GS} - V_T)^2 [1 + \lambda(V_{DS})]$$

Channel Length Modulation

3). Sub-threshold (Cutoff) Region:  $V_{GS} \leq V_T$

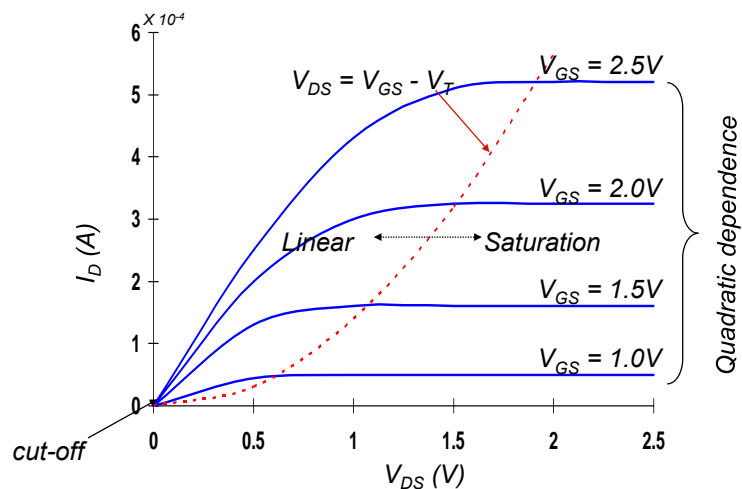
$$I_D \doteq 0$$

## Current Determinates

□ For a fixed  $V_{DS}$  and  $V_{GS} (> V_T)$ ,  $I_{DS}$  is a function of

- the distance between the source and drain –  $L$
- the channel width –  $W$
- the threshold voltage –  $V_T$
- the thickness of the  $\text{SiO}_2$  –  $t_{ox}$
- the dielectric of the gate insulator ( $\text{SiO}_2$ ) –  $\epsilon_{ox}$
- the carrier mobility
  - for nfets:  $\mu_n = 500 \text{ cm}^2/\text{V-sec}$
  - for pfets:  $\mu_p = 180 \text{ cm}^2/\text{V-sec}$

## Long Channel I-V Plot (NMOS)



NMOS transistor,  $0.25\mu\text{m}$ ,  $L_d = 10\mu\text{m}$ ,  $W/L = 1.5$ ,  $V_{DD} = 2.5\text{V}$ ,  $V_T = 0.4\text{V}$

## Second Order Effects

### • Channel Length Modulation

- Square Law Equation predicts  $I_D$  is constant with  $V_{DS}$
- However,  $I_D$  actually increases slightly with  $V_{DS}$ 
  - due to **effective channel getting shorter as  $V_{DS}$  increases**
  - effect called **channel length modulation**
- Channel Length Modulation factor,  $\lambda$ 
  - models change in channel length with  $V_{DS}$
- Corrected  $I_D$  equation

$$I_D = \frac{\mu_n C_{ox} W}{2L} (V_{GS} - V_T)^2 (1 + \lambda(V_{DS} - V_{eff}))$$

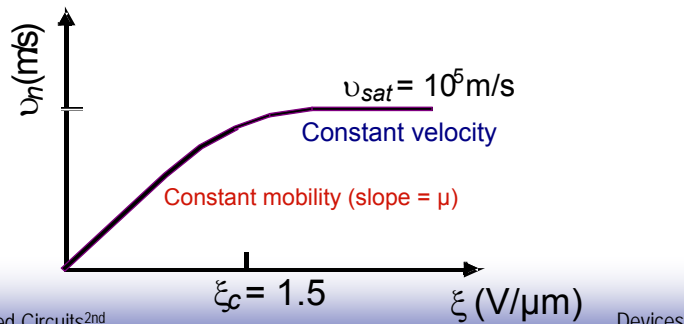
•  $V_{eff} = V_{GS} - V_{tn}$

### • Body Effect

- so far we have assumed that substrate and source are grounded
- if source not at ground, source-to-bulk voltage exists,  $V_{SB} > 0$
- $V_{SB} > 0$  will **increase the threshold voltage**,  $V_{tn} = f(V_{SB})$
- called **Body Effect**, or **Body-Bias Effect**

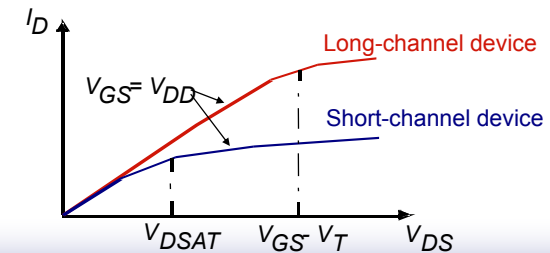
## Velocity Saturation

- For long channel device: carrier velocity increases linearly with E-field:  
 $v_n = -\mu_n \xi(x) = \mu_n (dV/dx)$
- For transistors with very short channel length (short-channel devices), when E-field along the channel reaches a critical value  $\xi_c$ , the velocity of carriers saturates due to scattering effects (collisions suffered by carriers).

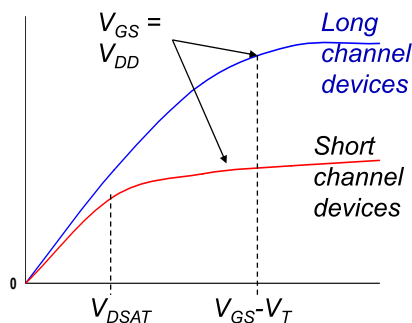


## Perspective

- For short channel transistor, due to velocity saturation:
  - Transistor enters saturation before  $V_{DS}$  reaches  $V_{GS} - V_T$ . Short-channel devices experience extended saturation region, and tend to operation more often in saturation conditions.
  - Saturation current  $I_{DSAT}$  shows linear dependence to  $V_{GS}$  instead of squared dependence in long-channel device. This reduces the amount of current a transistor can deliver for a given control voltage.



## Velocity Saturation Effects



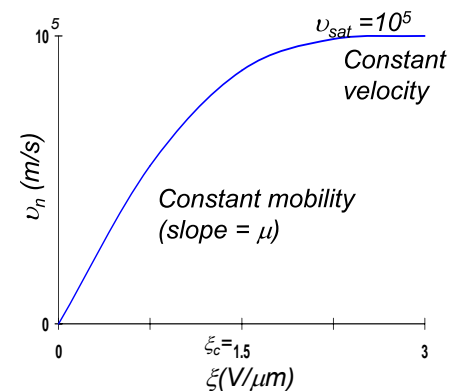
For short channel devices and large enough  $V_{GS} - V_T$

- $V_{DSAT} < V_{GS} - V_T$  so the device enters saturation before  $V_{DS}$  reaches  $V_{GS} - V_T$  and operates more often in saturation

- $I_{DSAT}$  has a linear dependence wrt  $V_{GS}$  so a reduced amount of current is delivered for a given control voltage

## Short Channel Effects

- Behavior of short channel device mainly due to



- Velocity saturation – the velocity of the carriers saturates due to scattering (collisions suffered by the carriers)

- For an NMOS device with  $L$  of  $.25\mu\text{m}$ , only a couple of volts difference between  $D$  and  $S$  are needed to reach velocity saturation

## Voltage-Current Relation: Velocity Saturation

For short channel devices

□ Linear: When  $V_{DS} \leq V_{GS} - V_T$

$$I_D = \kappa(V_{DS}) k'_n W/L [(V_{GS} - V_T)V_{DS} - V_{DS}^2/2]$$

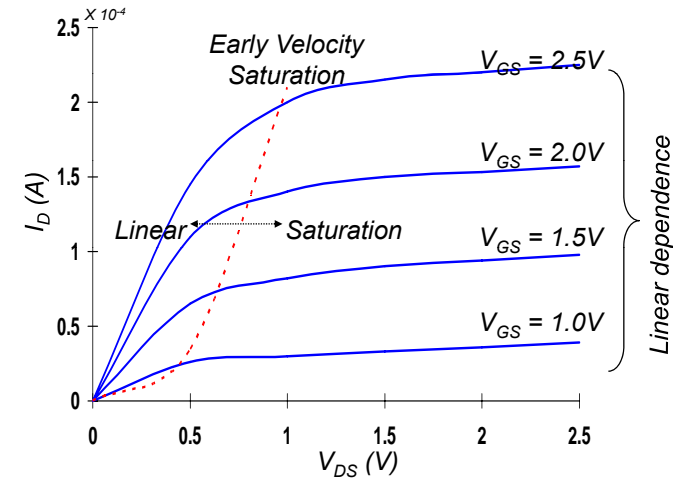
where

$\kappa(V) = 1/(1 + (V/\xi_c L))$  is a measure of the degree of velocity saturation

□ Saturation: When  $V_{DS} = V_{DSAT} \geq V_{GS} - V_T$

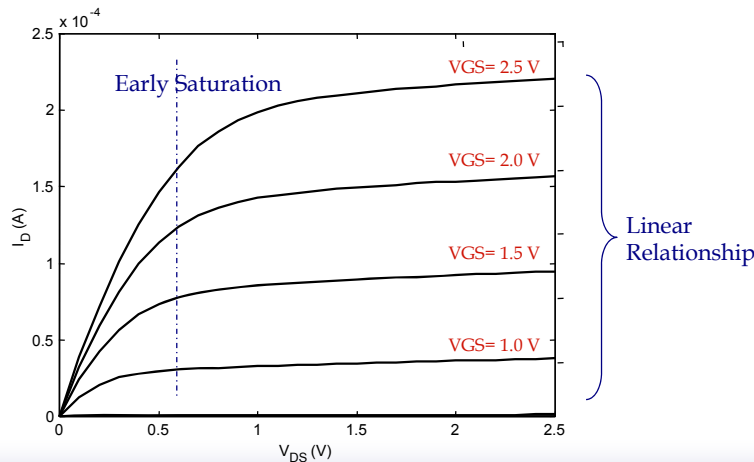
$$I_{DSAT} = \kappa(V_{DSAT}) k'_n W/L [(V_{GS} - V_T)V_{DSAT} - V_{DSAT}^2/2]$$

## Short Channel I-V Plot (NMOS)

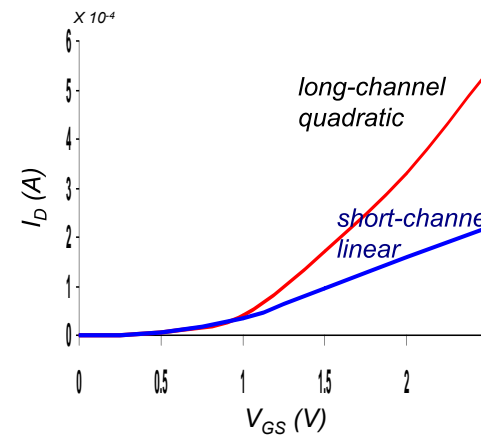


NMOS transistor,  $0.25\mu m$ ,  $L_d = 0.25\mu m$ ,  $W/L = 1.5$ ,  $V_{DD} = 2.5V$ ,  $V_T = 0.4V$

## Current-Voltage Relations The Deep-Submicron Era



## MOS $I_D$ - $V_{GS}$ Characteristics

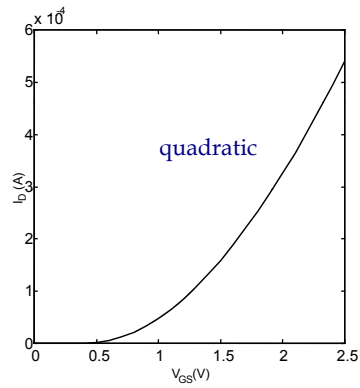


- Linear (short-channel) versus quadratic (long-channel) dependence of  $I_D$  on  $V_{GS}$  in saturation

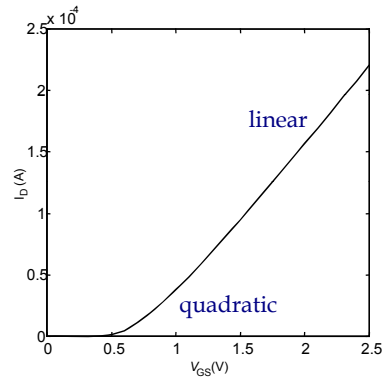
- Velocity-saturation causes the short-channel device to saturate at substantially smaller values of  $V_{DS}$  resulting in a substantial drop in current drive

(for  $V_{DS} = 2.5V$ ,  $W/L = 1.5$ )

## $I_D$ versus $V_{GS}$

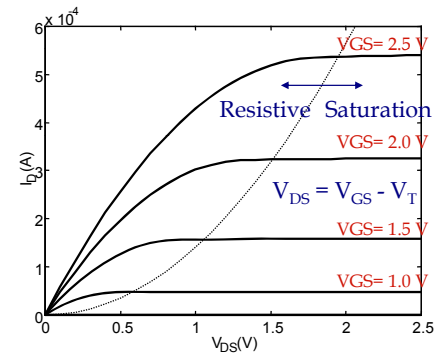


Long Channel

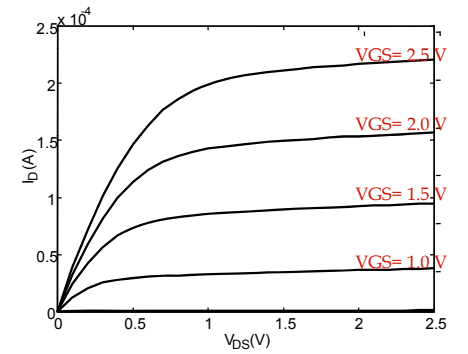


Short Channel

## $I_D$ versus $V_{DS}$

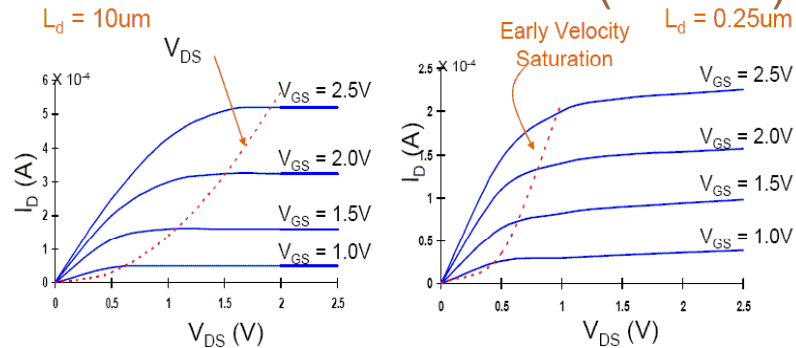


Long Channel



Short Channel

## Short Channel I-V Plot (NMOS)

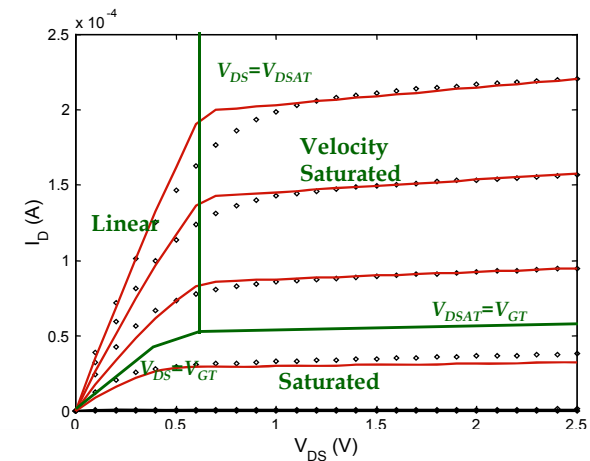


Quadratic dependence on  $V_{GS}$

Linear dependence on  $V_{GS}$

- $I_{DSAT}$  has a **linear dependence** with respect to  $V_{GS}$  (as opposed to quadratic) so a reduced amount of current is delivered for a given control voltage

## Simple Model versus SPICE

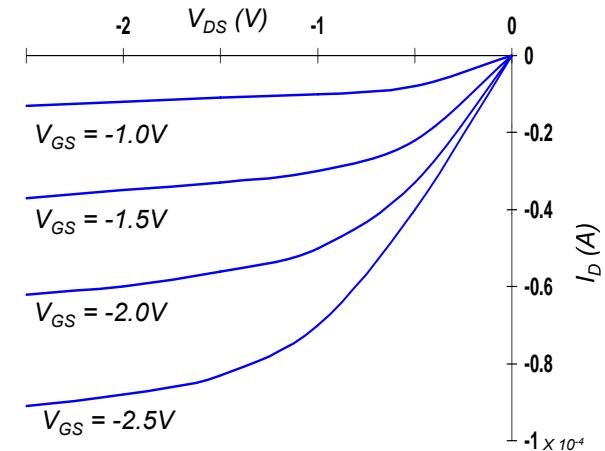


## pMOS Equations

- Analysis of nMOS applies to pMOS with following modifications
  - physical
    - change all n-type regions to p-type
    - change all p-type regions to n-type
      - substrate is n-type (nWell)
    - channel charge is positive (holes) and (+)ve charged ions
  - equations
    - change  $V_{GS}$  to  $V_{SG}$  ( $V_{SG}$  typically =  $V_{DD} - V_G$ )
    - change  $V_{DS}$  to  $V_{SD}$  ( $V_{SD}$  typically =  $V_{DD} - V_D$ )
    - change  $V_{tn}$  to  $|V_{tp}|$ 
      - pMOS threshold is negative, nearly same magnitude as nMOS
  - other factors
    - lower surface mobility, typical value,  $\mu_p = 220 \text{ cm}^2/\text{V-sec}$
    - body effect, change  $V_{SB}$  to  $V_{BS}$

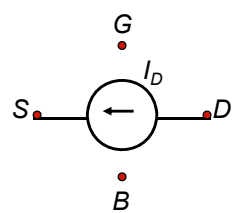
## Short Channel I-V Plot (PMOS)

- All polarities of all voltages and currents are reversed



PMOS transistor,  $0.25\mu\text{m}$ ,  $L_d = 0.25\mu\text{m}$ ,  $W/L = 1.5$ ,  $V_{DD} = 2.5\text{V}$ ,  $V_T = -0.4\text{V}$   
© Digital Integrated Circuits<sup>2nd</sup> Devices

## The MOS Current-Source Model



$$I_D = 0 \text{ for } V_{GS} - V_T \leq 0$$

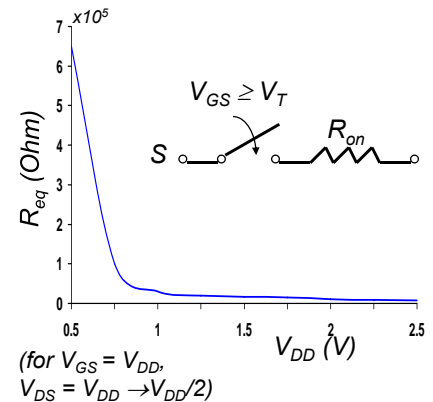
$$I_D = k' W/L [(V_{GS} - V_T)V_{min} - V_{min}^2/2](1 + \lambda V_{DS}) \text{ for } V_{GS} - V_T \geq 0$$

with  $V_{min} = \min(V_{GS} - V_T, V_{DS}, V_{DSAT})$   
and  $V_{GT} = V_{GS} - V_T$

- Determined by the voltages at the four terminals and a set of five device parameters

	$V_{T0}$ (V)	$\gamma$ (V <sup>0.5</sup> )	$V_{DSAT}$ (V)	$k'$ (A/V <sup>2</sup> )	$\lambda$ (V <sup>-1</sup> )
NMOS	0.43	0.4	0.63	$115 \times 10^{-6}$	0.06
PMOS	-0.4	-0.4	-1	$-30 \times 10^{-6}$	-0.1

## The Transistor Modeled as a Switch



Modeled as a switch with infinite off resistance and a finite on resistance,  $R_{on}$

- Resistance inversely proportional to  $W/L$  (doubling  $W$  halves  $R_{on}$ )
- For  $V_{DD} \gg V_T + V_{DSAT}/2$ ,  $R_{on}$  independent of  $V_{DD}$
- Once  $V_{DD}$  approaches  $V_T$ ,  $R_{on}$  increases dramatically

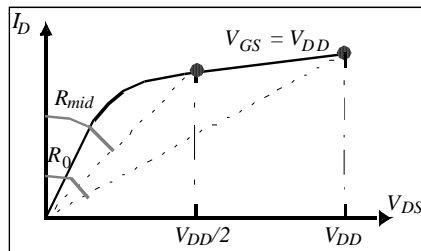
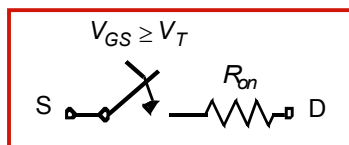
$V_{DD}$ (V)	1	1.5	2	2.5
NMOS(k $\Omega$ )	35	19	15	13
PMOS (k $\Omega$ )	115	55	38	31

$R_{on}$  (for  $W/L = 1$ )  
For larger devices divide  $R_{eq}$  by  $W/L$



## The Transistor as a Switch

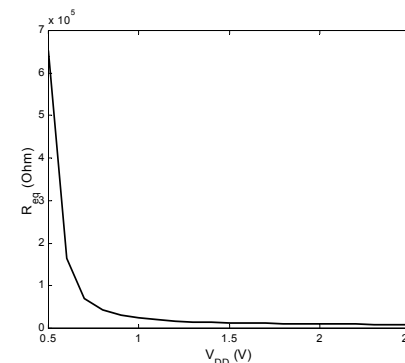
- In digital VLSI, transistor is treated as a switch with infinite “off” resistance, and a finite “on” resistance  $R_{on}$ .
- $R_{on}$  is time varying, nonlinear and dependent on transistor operating point. We can use the average value of resistances at the end points of the transition.
- $R_{eq}$  is inversely proportional to  $(W/L)$  ratio of transistor. Doubling the transistor width cuts the resistance in half. ( $I_{DSAT}$  is linear to  $(W/L)$ )



$$R_{eq} = \frac{1}{2} \left( \frac{V_{DD}}{I_{DSAT}(1+\lambda V_{DD})} + \frac{V_{DD}/2}{I_{DSAT}(1+\lambda V_{DD}/2)} \right) \approx \frac{3}{4} \frac{V_{DD}}{I_{DSAT}} \left( 1 - \frac{5}{6} \lambda V_{DD} \right)$$

## The Transistor as a Switch

- For  $V_{DD} \gg V_T + V_{DSAT}/2$ ,  $R_{eq}$  is virtually independent of  $V_{DD}$ . On a minor increase on  $R_{eq}$  due to channel length modulation can be observed when raising  $V_{DD}$ .
- Once  $V_{DD} \rightarrow V_T$ ,  $R_{eq}$  increases dramatically.



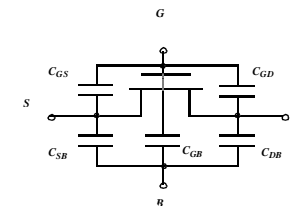
## MOS Capacitances Dynamic Behavior



## Capacitances of MOS Transistor

- MOS capacitances according to physical mechanisms
  - Overlap capacitances:  $C_{gso}, C_{gdo}$
  - Channel capacitances:  $C_{gs}, C_{gd}, C_{gb}$
  - Diffusion capacitance:  $C_{Sdiff}, C_{Ddiff}$
- Lumped capacitance model of MOS transistor: capacitances between terminals without considering physical mechanisms

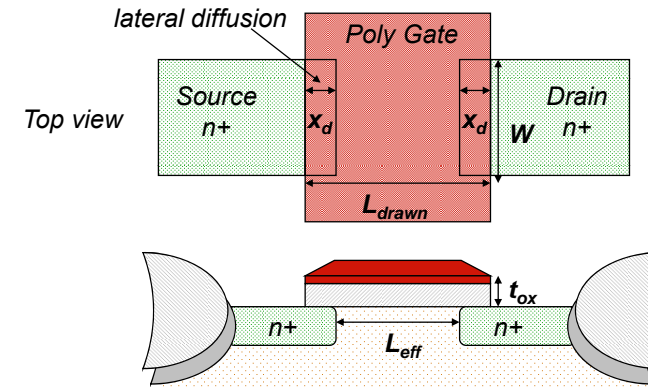
$$\begin{aligned} C_{GS} &= C_{gs} + C_{gso} \\ C_{GD} &= C_{gd} + C_{gdo} \\ C_{GB} &= C_{gb} \\ C_{SB} &= C_{Sdiff} \\ C_{DB} &= C_{Ddiff} \end{aligned}$$



## MOS Intrinsic Capacitances

- Structure capacitances
- Channel capacitances
- Depletion regions of the reverse-biased  $pn$ -junctions of the drain and source

## MOS Structure Capacitances



Overlap capacitance (linear)

$$C_{GSO} = C_{GDO} = C_{ox} x_d W = C_o W$$

## MOS Capacitances: Structure Capacitances

- MOS structure capacitance: originate from MOS structure

1). Gate capacitance  $C_g$

$$C_g = C_{ox} W \cdot L, \text{ where } C_{ox} = \epsilon_{ox} / t_{ox}$$

Lateral diffusion: during to fabrication, both source and drain tends to extend somewhat below the oxide by  $x_d$ .

Effective channel length:

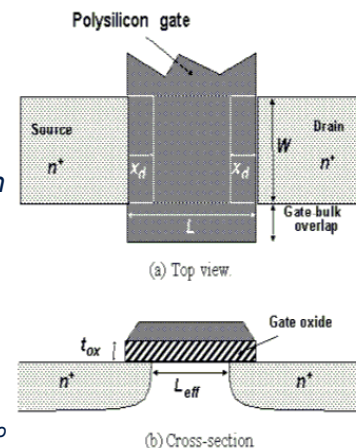
$$L_{eff} = L - 2x_d$$

Gate capacitance considering  $x_d$ :

$$C_g = C_{ox} W \cdot L_{eff}$$

2). Overlap capacitance:  $C_{gso}, C_{gdo}$

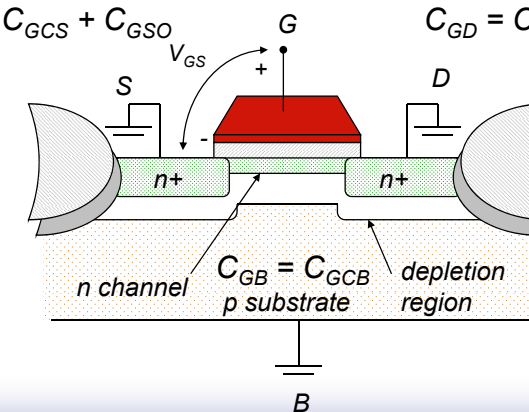
$$C_{gso} = C_{gdo} = C_{ox} \cdot x_d \cdot W$$



## MOS Channel Capacitances

- The gate-to-channel capacitance depends upon the operating region and the terminal voltages

$$C_{GS} = C_{GCS} + C_{GSO} \quad C_{GD} = C_{GCD} + C_{GDO}$$



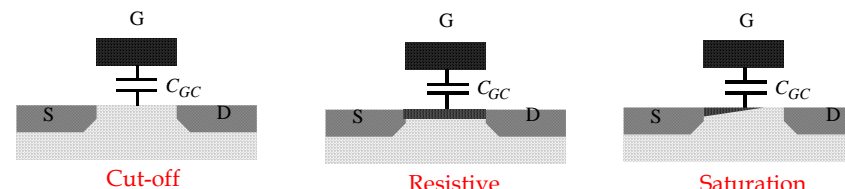
## Review: Summary of MOS Operating Regions

- Cutoff (really subthreshold)  $V_{GS} \leq V_T$ 
  - Exponential in  $V_{GS}$  with linear  $V_{DS}$  dependence  
 $I_D = I_S e^{(qV_{GS}/nkT)} (1 - e^{-(qV_{DS}/kT)}) (1 - \lambda V_{DS})$  where  $n \geq 1$
- Strong Inversion  $V_{GS} > V_T$ 
  - Linear (Resistive)  $V_{DS} < V_{DSAT} = V_{GS} - V_T$   
 $I_D = k' W/L [(V_{GS} - V_T)V_{DS} - V_{DS}^2/2] (1 + \lambda V_{DS}) \kappa(V_{DS})$
  - Saturated (Constant Current)  $V_{DS} \geq V_{DSAT} = V_{GS} - V_T$   
 $I_{DSat} = k' W/L [(V_{GS} - V_T)V_{DSAT} - V_{DSAT}^2/2] (1 + \lambda V_{DS}) \kappa(V_{DSAT})$

	$V_{T0}(V)$	$\gamma(V^{0.5})$	$V_{DSAT}(V)$	$k'(A/V^2)$	$\lambda(V^{-1})$
NMOS	0.43	0.4	0.63	$115 \times 10^{-6}$	0.06
PMOS	-0.4	-0.4	-1	$-30 \times 10^{-6}$	-0.1

## Channel Capacitance

- MOS channel capacitances: originate from channel charge
- MOS gate-to-channel capacitances:  $C_{gb}$ ,  $C_{gs}$ ,  $C_{gd}$
- Distribution of gate capacitance among channel capacitances depends on operating conditions.



MOS gate-to-channel capacitances in different operation regions

Operation Region	$C_{gb}$	$C_{gs}$	$C_{gd}$
Cutoff	$C_{ox}WL_{eff}$	0	0
Triode	0	$C_{ox}WL_{eff}/2$	$C_{ox}WL_{eff}/2$
Saturation	0	$(2/3)C_{ox}WL_{eff}$	0

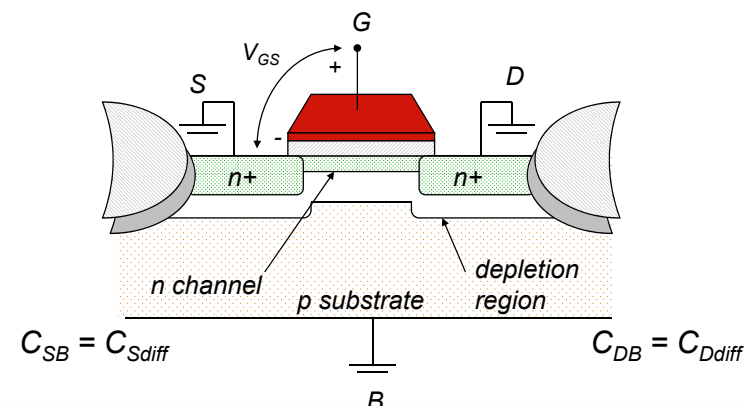
## Average Distribution of Channel Capacitance

Operation Region	$C_{GCB}$	$C_{GCS}$	$C_{GCD}$	$C_{GC}$	$C_G$
Cutoff	$C_{ox}WL$	0	0	$C_{ox}WL$	$C_{ox}WL + 2C_oW$
Resistive	0	$C_{ox}WL/2$	$C_{ox}WL/2$	$C_{ox}WL$	$C_{ox}WL + 2C_oW$
Saturation	0	$(2/3)C_{ox}WL$	0	$(2/3)C_{ox}WL$	$(2/3)C_{ox}WL + 2C_oW$

- Channel capacitance components are nonlinear and vary with operating voltage
- Most important regions are cutoff and saturation since that is where the device spends most of its time

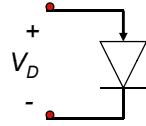
## MOS Diffusion Capacitances

- The junction (or diffusion) capacitance is from the reverse-biased source-body and drain-body pn-junctions.



## Review: Reverse Bias Diode

- All diodes in MOS digital circuits are reverse biased; the dynamic response of the diode is determined by depletion-region charge or **junction capacitance**



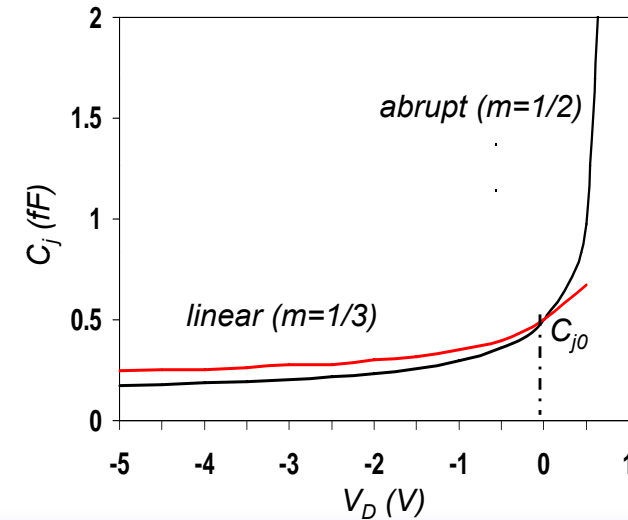
$$C_j = C_{j0} / ((1 - V_D) / \phi_0)^m$$

where  $C_{j0}$  is the capacitance under zero-bias conditions (a function of physical parameters),  $\phi_0$  is the built-in potential (a function of physical parameters and temperature)

and  $m$  is the grading coefficient

- $m = 1/2$  for an **abrupt** junction (transition from n to p-material is instantaneous)
  - $m = 1/3$  for a **linear** (or graded) junction (transition is gradual)
- Nonlinear dependence (that decreases with increasing reverse bias)

## Reverse-Bias Diode Junction Capacitance



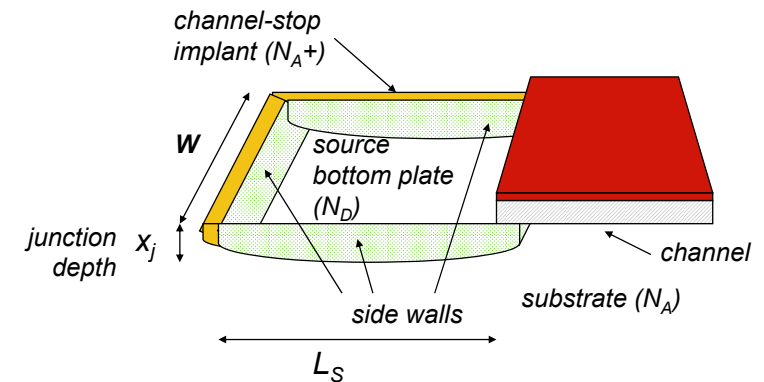
## Linearizing the Junction Capacitance

Replace non-linear capacitance by **large-signal equivalent linear capacitance** which displaces equal charge over voltage swing of interest

$$C_{eq} = \frac{\Delta Q_j}{\Delta V_D} = \frac{Q_j(V_{high}) - Q_j(V_{low})}{V_{high} - V_{low}} = K_{eq} C_{j0}$$

$$K_{eq} = \frac{-\phi_0^m}{(V_{high} - V_{low})(1 - m)} [(\phi_0 - V_{high})^{1-m} - (\phi_0 - V_{low})^{1-m}]$$

## Source Junction View



$$C_{diff} = C_{bp} + C_{sw} = C_j \text{ AREA} + C_{jsw} \text{ PERIMETER}$$

$$= C_j L_S W + C_{jsw} (2L_S + W)$$

### MOS Capacitances: Junction/Diffusion Capacitances

- MOS junction/diffusion capacitances ( $C_{Sdiff}$ ,  $C_{Ddiff}$ ): originate from depletion regions of reversed-biased pn-junctions of drain and source

$C_{Sdiff}$ : for source-bulk pn-junction

$C_{Ddiff}$ : for drain-bulk pn-junction

- Let's define

$C_j$ : junction capacitance per unit area

$C_{jsw}$ : sidewall junction capacitance per unit area

$x_j$ : junction depth

$W$ : channel width

$L_S$ : source length

$L_D$ : drain length

### MOS Capacitances: Junction/Diffusion Capacitances

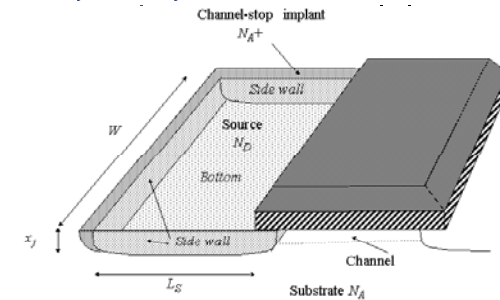
- For  $C_{Sdiff}$ :

1). Bottom plate junction:  $C_{S\_bottom} = C_j W L_S$

2). Side-wall junctions (3 sidewalls):  $C_{S\_sw} = C_{jsw} x_j (W + 2L_S)$

➔ Total  $C_{Sdiff} = C_{S\_bottom} + C_{S\_sw} = C_j W L_S + C_{jsw} (W + 2L_S)$

- Total  $C_{Ddiff} = C_j L_D W + C_{jsw} (W + 2L_D)$

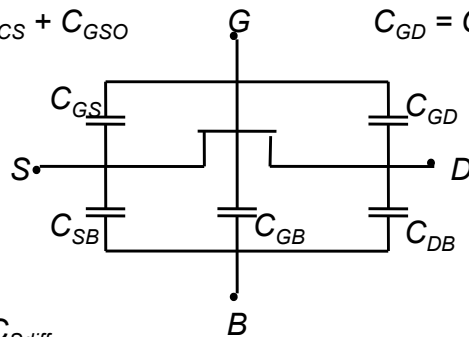


$$C_{diff} = C_{bottom} + C_{sw} = C_j \times AREA + C_{jsw} \times PERIMETER$$

$$= C_j L_S W + C_{jsw} (2L_S + W)$$

### MOS Capacitance Model

$$C_{GS} = C_{GCS} + C_{GSO} \quad C_{GD} = C_{GCD} + C_{GDO}$$



$$C_{SB} = C_{Sdiff}$$

$$C_{DB} = C_{Ddiff}$$

$$C_{GB} = C_{GCB}$$

### Transistor Capacitance Values for 0.25μ

Example: For an NMOS with  $L = 0.24 \mu m$ ,  $W = 0.36 \mu m$ ,  
 $L_D = L_S = 0.625 \mu m$

$$C_{GSO} = C_{GDO} = C_{ox} x_d W = C_o W = 0.11 \text{ fF}$$

$$C_{GC} = C_{ox} WL = 0.52 \text{ fF}$$

$$\text{so } C_{gate\_cap} = C_{ox} WL + 2C_o W = 0.74 \text{ fF}$$

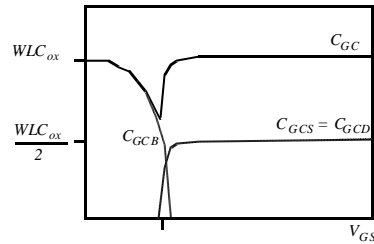
$$C_{bp} = C_j L_S W = 0.45 \text{ fF}$$

$$C_{sw} = C_{jsw} (2L_S + W) = 0.45 \text{ fF}$$

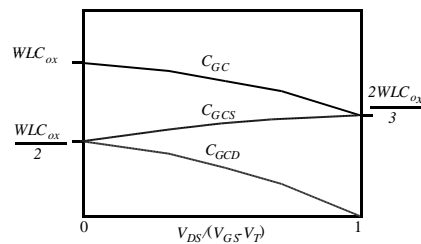
$$\text{so } C_{diffusion\_cap} = 0.90 \text{ fF}$$

	$C_{ox}$ (fF/ $\mu m^2$ )	$C_o$ (fF/ $\mu m$ )	$C_j$ (fF/ $\mu m^2$ )	$m_j$	$\phi_b$ (V)	$C_{jsw}$ (fF/ $\mu m$ )	$m_{jsw}$	$\phi_{bsw}$ (V)
NMOS	6	0.31	2	0.5	0.9	0.28	0.44	0.9
PMOS	6	0.27	1.9	0.48	0.9	0.22	0.32	0.9

## Gate Capacitance

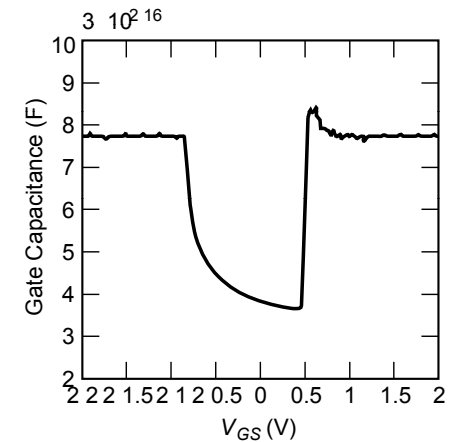
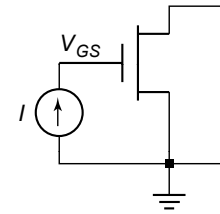


Capacitance as a function of  $V_{GS}$  (with  $V_{DS} = 0$ )



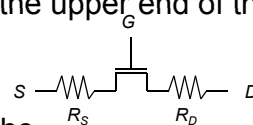
Capacitance as a function of the degree of saturation

## Measuring the Gate Cap



## Other (Submicron) MOS Transistor Concerns

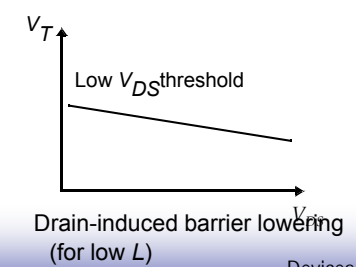
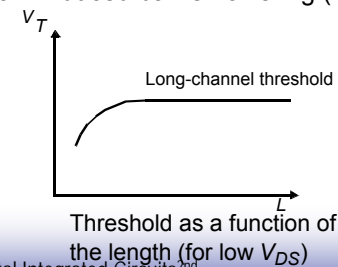
- Velocity saturation
- Subthreshold conduction
  - Transistor is already partially conducting for voltages below  $V_T$
- Threshold variations
  - In long-channel devices, the threshold is a function of the length (for low  $V_{DS}$ )
  - In short-channel devices, there is a drain-induced threshold barrier lowering at the upper end of the  $V_{DS}$  range (for low  $L$ )
- Parasitic resistances
  - resistances associated with the source and drain contacts



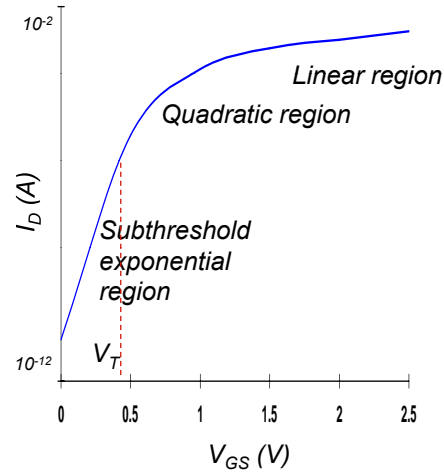
### □ Latch-up

## Threshold Variations

- For short-channel transistors:
  - ✓ The depletion regions of source and reverse-biased drain junction, previously was ignored in long-channel device. But for short-channel device, they become relatively more important with shrinking channel length. Since a part of the region below gate is already depleted, a smaller  $V_T$  suffices to cause strong inversion. Thus,  $V_{TO}$  decreased with  $L$  for short-channel device.
  - ✓ Raising drain-source (bulk) voltage also increases the width of drain-junction depletion region, hence  $V_{TO}$  decreases with increasing  $V_{DS}$ : drain-induced barrier lowering (DIBL).



# Subthreshold Conductance



- Transition from ON to OFF is gradual (decays exponentially)
- Current roll-off (slope factor) is also affected by increase in temperature

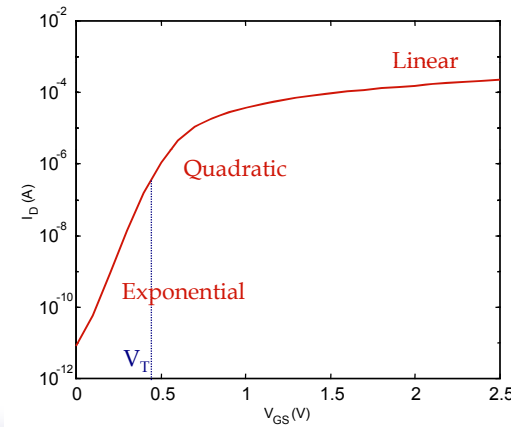
$$S = n (kT/q) \ln(10)$$

(typical values 60 to 100 mV/decade)

- Has repercussions in dynamic circuits and for power consumption

$$I_D \sim I_S e^{(qV_{GS}/nkT)} \text{ where } n \geq 1$$

# Sub-Threshold Conduction



## The Slope Factor

$$I_D \sim I_0 e^{\frac{qV_{GS}}{nkT}}, \quad n = 1 + \frac{C_D}{C_{ox}}$$

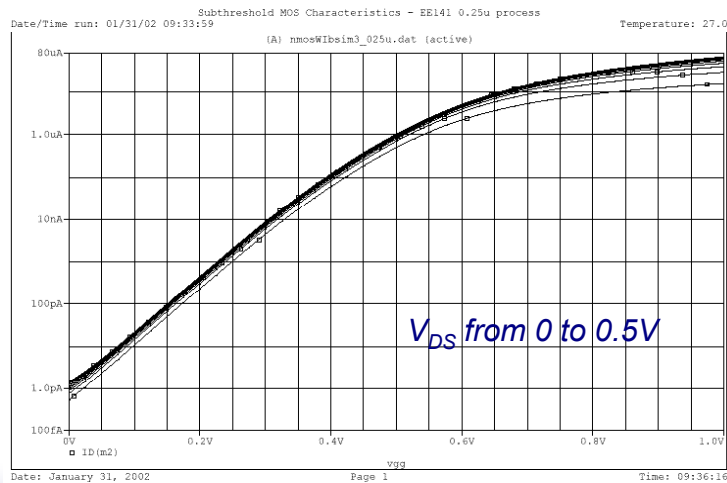
S is  $\Delta V_{GS}$  for  $I_{D2}/I_{D1} = 10$

$$S = n \left( \frac{kT}{q} \right) \ln(10)$$

Typical values for S: 60 .. 100 mV/decade

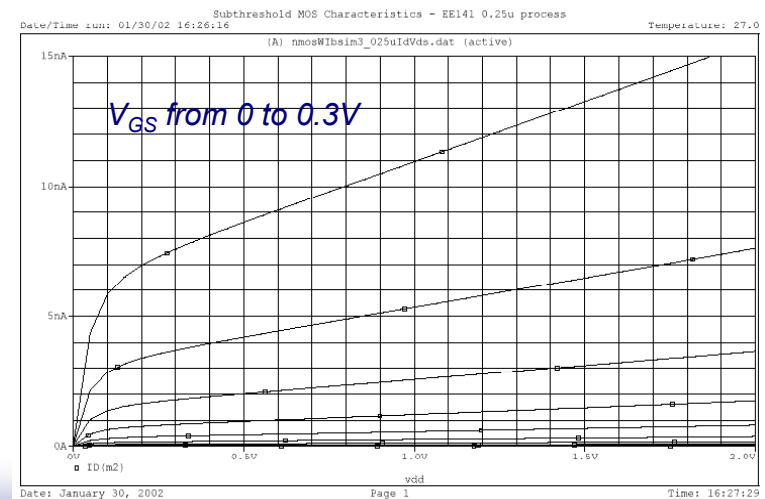
# Subthreshold $I_D$ vs $V_{GS}$

$$I_D = I_S e^{(qV_{GS}/nkT)} (1 - e^{-(qV_{DS}/kT)}) (1 + \lambda V_{DS})$$



# Subthreshold $I_D$ vs $V_{DS}$

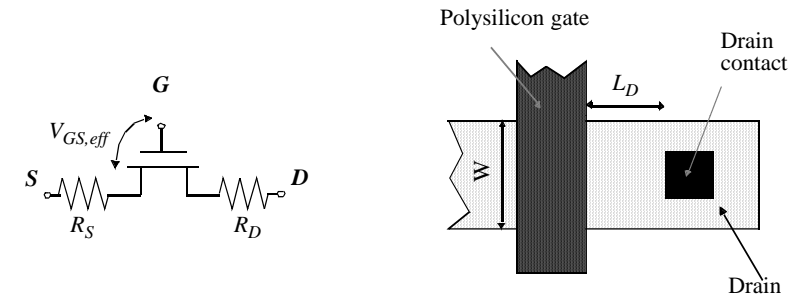
$$I_D = I_S e^{(qV_{GS}/nkT)} (1 - e^{-(qV_{DS}/kT)}) (1 + \lambda V_{DS})$$



## Summary of MOSFET Operating Regions

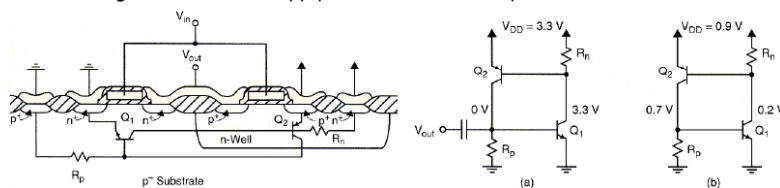
- Strong Inversion  $V_{GS} > V_T$ 
  - Linear (Resistive)  $V_{DS} < V_{DSAT}$
  - Saturated (Constant Current)  $V_{DS} \geq V_{DSAT}$
- Weak Inversion (Sub-Threshold)  $V_{GS} \leq V_T$ 
  - Exponential in  $V_{GS}$  with linear  $V_{DS}$  dependence

## Parasitic Resistances



## Latch-Up

- Latch-up is a very real, very important factor in circuit design that must be accounted for
- Due to (relatively) large current in substrate or n-well
  - create voltage drops across the resistive substrate/well
    - most common during large power/ground current spikes
  - turns on parasitic BJT devices, **effectively shorting power & ground**
    - often results in device failure with fused-open wire bonds or interconnects
  - **hot carrier effects** can also result in latch-up
    - latch-up very important for short channel devices
- **Avoid latch-up** by
  - including as many substrate/well contacts as possible
    - rule of thumb: one "plug" each time a tx connects to the power rail
  - limiting the maximum supply current on the chip



## SPICE MODELS

**Level 1: Long Channel Equations - Very Simple**

**Level 2: Physical Model - Includes Velocity Saturation and Threshold Variations**

**Level 3: Semi-Emperical - Based on curve fitting to measured devices**

**Level 4 (BSIM): Emperical - Simple and Popular**



## MAIN MOS SPICE PARAMETERS

Parameter Name	Symbol	SPICE Name	Units	Default Value
SPICE Model Index		LEVEL	-	1
Zero-Bias Threshold Voltage	VT0	VT0	V	0
Process Transconductance	k'	KP	A/V <sup>2</sup>	2.E-5
Body-Bias Parameter	g	GAMMA	V0.5	0
Channel Modulation	1	LAMBDA	1/V	0
Oxide Thickness	tox	TOX	m	1.0E-7
Lateral Diffusion	xd	LD	m	0
Metallurgical Junction Depth	xj	XJ	m	0
Surface Inversion Potential	2 φ <sub>F</sub>	PHI	V	0.6
Substrate Doping	N <sub>A,ND</sub>	NSUB	cm-3	0
Surface State Density	Q <sub>ss</sub> /q	NSS	cm-3	0
Fast Surface State Density		NFS	cm-3	0
Total Channel Charge Coefficient		NEFF	-	1
Type of Gate Material		TPG	-	1
Surface Mobility	m0	U0	cm <sup>2</sup> /V-sec	600
Maximum Drift Velocity	umax	VMAX	m/s	0
Mobility Critical Field	xcrit	UCRIT	V/cm	1.0E4
Critical Field Exponent in Mobility Degradation		UEXP	-	0
Transverse Field Exponent (mobility)		UTRA	-	0

## SPICE Parameters for Parasitics

Parameter Name	Symbol	SPICE Name	Units	Default Value
Source resistance	$R_S$	RS	Ω	0
Drain resistance	$R_D$	RD	Ω	0
Sheet resistance (Source/Drain)	$R_o$	RSH	Ω/□	0
Zero Bias Bulk Junction Cap	$C_{j0}$	CJ	F/m <sup>2</sup>	0
Bulk Junction Grading Coeff.	$m$	MJ	-	0.5
Zero Bias Side Wall Junction Cap	$C_{jsw0}$	CJSW	F/m	0
Side Wall Grading Coeff.	$m_{sw}$	MJSW	-	0.3
Gate-Bulk Overlap Capacitance	$C_{gb0}$	CGBO	F/m	0
Gate-Source Overlap Capacitance	$C_{gs0}$	CGSO	F/m	0
Gate-Drain Overlap Capacitance	$C_{gd0}$	CGDO	F/m	0
Bulk Junction Leakage Current	$I_S$	IS	A	0
Bulk Junction Leakage Current Density	$J_S$	JS	A/m <sup>2</sup>	1E-8
Bulk Junction Potential	$φ_0$	PB	V	0.8

## SPICE Transistors Parameters

Parameter Name	Symbol	SPICE Name	Units	Default Value
Drawn Length	L	L	m	-
Effective Width	W	W	m	-
Source Area	AREA	AS	m <sup>2</sup>	0
Drain Area	AREA	AD	m <sup>2</sup>	0
Source Perimeter	PERIM	PS	m	0
Drain Perimeter	PERIM	PD	m	0
Squares of Source Diffusion		NRS	-	1
Squares of Drain Diffusion		NRD	-	1